



## Gases and Facilities Japan Joint TC Chapter Meeting Summary and Minutes (Draft)

SEMI Japan Standards Summer 2018 Meetings

June 29, 2018, Begin [14:00] – End [17:00]

SEMI Japan, Tokyo, Japan

### TC Chapter Announcements

*Next TC Chapter Meeting*

Gases and Facilities Japan Joint TC Chapter

The next meeting is scheduled at 14:00 for Friday, November 30, 2018 at SEMI Japan, Tokyo, Japan.

### Table 1 Meeting Attendees

*Italics indicate virtual participants*

**Gases Japan TC Chapter Co-Chairs:** Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan)

**Facilities Japan TC Chapter Co-Chairs:** Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan)

**SEMI Staff:** Mizue Iwamura

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Daido Steel	Matsuda	Mitsuhiro	NISSAN TANAKA	Takamisawa	Kazuhiko
Fujikin	Kitano	Masafumi	Tri Chemical Laboratories	Hiraki	Tadaaki
Hitachi High-Technologies	Enami	Hiromichi			
MKS Japan	Suzuki	Isao	SEMI Japan	Iwamura	Mizue

### Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
<i>Gases Japan TC Chapter</i>		
Gases Japan TC Chapter	Tsuneyuki Okabe (Tokyo Electron Tohoku)	-
<i>Facilities Japan TC Chapter</i>		
Facilities Japan TC Chapter	Tsuneyuki Okabe (Tokyo Electron Tohoku)	-

**Table 3 Committee Structure Changes**

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
<i>Gases Japan TC Chapter</i>	
None.	
<i>Facilities Japan TC Chapter</i>	
None.	

**Table 4 Ballot Results**

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
<i>Gases Japan TC Chapter</i>		
None.		
<i>Facilities Japan TC Chapter</i>		
None.		

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

**Table 5 Activities Approved by the GCS between meetings of the TC Chapter**

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
<i>Gases Japan TC Chapter</i>			
None.			
<i>Facilities Japan TC Chapter</i>			
None.			

**Table 6 Authorized Activities**

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
<i>Gases Japan TC Chapter</i>			
None.			
<i>Facilities Japan TC Chapter</i>			
None.			

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

**Table 7 Authorized Ballots**

#	When	TF	Details
<i>Gases Japan TC Chapter</i>			
None.			
<i>Facilities Japan TC Chapter</i>			
None.			

**Table 8 SNARF(s) Granted a One-Year Extension**

#	TF	Title	Expiration Date
<i>Gases Japan TC Chapter</i>			
None.			
<i>Facilities Japan TC Chapter</i>			
None.			

**Table 9 SNARF(s) Abolished**

#	TF	Title
<i>Gases Japan TC Chapter</i>		
None.		
<i>Facilities Japan TC Chapter</i>		
None.		

**Table 10 Standard(s) to receive Inactive Status**

Standard Designation	Title
<i>Gases Japan TC Chapter</i>	
None.	
<i>Facilities Japan TC Chapter</i>	
None.	

**Table 11 New Action Items**

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
None.		

**Table 12 Previous Meeting Action Items**

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
20180424_01	Mizue Iwamura (SEMI Japan)	To make the list of SEMI Standards which originating TC chapter are Japan Gases and Facilities. OPEN
20180424_02	Tetsuo Shimizu (HORIBA STEC)	To provide the past 3 years activities reports of Live Gas Flow Rate Task Force. OPEN

## 1 Welcome, Reminders, and Introductions

Isao Suzuki called the meeting to order at 14:10. Isao Suzuki announced that Tsuneyuki Okabe (Tokyo Electron Tohoku) stepped down from co-chairs of Gases Japan TC Chapter and Facilities Japan TC Chapter due to some reasons.

The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

**Attachment:** 01\_02\_Required\_Elements\_Reg\_20150327\_E+J.pdf

## 2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

**Motion:** To approve the minutes of the previous meeting as written.

**By / 2<sup>nd</sup>:** Hiromichi Enami (Hitachi High-Technologies) / Masafumi Kitano (Fujikin)

**Discussion:** None.

**Vote:** 5 in favor and 0 opposed. **Motion passed.**

**Attachment:** 02-00\_20180424\_Miniutes\_Draft\_Gases and Facilities\_r2

### 3 Liaison Reports

#### 3.1 Facilities North America TC Chapter

None.

#### 3.2 Gases North America TC Chapter

None.

#### 3.3 Gases Europe TC Chapter

None.

#### 3.4 Facilities Korea TC Chapter

None.

#### 3.5 SEMI Staff Report

Mizue Iwamura (SEMI Japan) gave the SEMI Staff Report as attached.

**Attachment:** 03-05\_SEMI Staff Report 20180618\_v1.0

Hiromichi Enami (Hitachi High-Technologies) notified related meetings during SEMICON WEST as follows.

- Electrical Material Group (EMG) meeting is scheduled at 16:00 -17:00 on July 9<sup>th</sup>, 2018.
  - Venue: Moscone Center, Moscone South Hall, Room 215
  
- RF measurement TF meeting is scheduled at 13:30 – 15:00 on July 11<sup>th</sup>, 2018.
  - Venue: San Francisco Marriott Marquis, San Francisco, CA
    - ◇ This TF is currently reviewing SEMI Standards which were published more than 30 years ago.
  
- The Semiconductor Components, Instruments, and Subsystems (SCIS) is scheduled at 8:00 – 13:00 on July 11<sup>th</sup>, 2018
  - Venue: San Francisco, CA

\*Those schedules are as of June 29, 2018.

Hiromichi Enami (Hitachi High-Technologies) reported to the committee on this topic.

- Chemical & Gas Manufacturers Group (CGMG), the Silicon Manufacturers Group (SMG) and other SEMI member segments merged to the SEMI Electronic Materials Group (EMG).
  
- SCIS is focusing on EMI Standards which relates to gases now.

## 4 Ballot Review

1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

### 4.1 *Gases Japan TC Chapter*

None.

### 4.2 *Facilities Japan TC Chapter*

None.

## 5 Subcommittee and Task Force Reports

### 5.1 *Gases Japan TC Chapter*

None.

### 5.2 *Facilities Japan TC Chapter*

#### 5.2.1 F1 Revision Task Force

Masafumi Kitano (Fujikin) reported that F1 Revision Task Force will submit #6395: Revision to SEMI F1-0812, Specification for Leak Integrity of High Purity Gas Piping Systems and Components to revise specifications for leak check methods for Cycle 7-2018. First draft will be shared in July after reviewing negatives and comments which were received in Cycle2-2018. F1 Revision Task Force is still seeking new TF members.

#### 5.2.2 5-year-review Task Force

Masafumi Kitano (Fujikin) reported that 2 reapproval ballots below passed A&R.

- #6321: Reapproval of SEMI F45-0307, Specification for Machined Stainless Steel Reducing Weld
- #6322: Reapproval to SEMI F44-0307, Specification for Machined Stainless Steel Weld Fittings of Machined Stainless Steel Weld Fittings

## 6 Old Business

### 6.1 *Gases Japan TC Chapter*

#### 6.1.1 SNARF Project Period Check

Mizue Iwamura (SEMI Japan) addressed that there is no SNARF that exceed the project period.

#### 6.1.2 5 Year Review Check

Mizue Iwamura (SEMI Japan) addressed that there is no document to be addressed.

### 6.2 *Facilities Japan TC Chapter*

#### 6.2.1 SNARF Project Period Check

Mizue Iwamura (SEMI Japan) addressed that there is no SNARF that exceed the project period.

#### 6.2.2 5 Year Review Check

Mizue Iwamura (SEMI Japan) addressed that there is no document to be addressed.



## **7 New Business**

### *7.1 Gases Japan TC Chapter*

#### 7.1.1 Schedule Adjustment of meetings at SEMICON Japan 2018

Mizue Iwamura (SEMI Japan) will confirm whether schedule adjustment is possible or not to hold Gases and Facilities Japan TC Chapter Joint meeting during SEMICON Japan.

### *7.2 Facilities Japan TC Chapter*

#### 7.2.1 Collaboration with NA Facilities TC Chapter for the ballot #6395: Revision to SEMI F1-0812, Specification for Leak Integrity of High Purity Gas Piping Systems and Components (If any)

None.

#### 7.2.2 Schedule Adjustment of meetings at SEMICON Japan 2018

Mizue Iwamura (SEMI Japan) will confirm whether schedule adjustment is possible or not to hold Gases and Facilities Japan TC Chapter Joint meeting during SEMICON Japan.

#### 7.2.3 TF member recruitment for Seismic Protection TF under EHS Japan TC Chapter

Chie Yanagisawa (SEMI Japan) addressed committee on this topic. Seismic Protection TF under EHS Japan TC Chapter is currently seeking TF members who involved in construction companies or/and design companies relates to semiconductor industries. Detailed information will be announced by Chie Yanagisawa (SEMI Japan) by an e-mail to Facilities TC members in Japan.

## **8 Next Meeting and Adjournment**

The next meeting is scheduled at 14:00 for Friday, November 30, 2018 at SEMI Japan, Tokyo, Japan or during SEMICON Japan at Tokyo Big Sight, Tokyo, Japan.

See <http://www.semi.org/standards-events> for the current list of events.

Adjournment: 16:30.



Respectfully submitted by:  
Mizue Iwamura  
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SEMI Japan  
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Email: miwamura@semi.org

Minutes tentatively approved by:

Hiromichi Enami (Hitachi High Technologies), Gases Japan TC Chapter Co-chair	October 9, 2018
Isao Suzuki (MKS Japan), Gases Japan TC Chapter Co-chair	October 9, 2018
Hiromichi Enami (Hitachi High Technologies), Facilities Japan TC Chapter Co-chair	October 9, 2018
Isao Suzuki (MKS Japan), Facilities Japan TC Chapter Co-chair	October 9, 2018

**Table 13 Index of Available Attachments#1**

<i>Title</i>	<i>Title</i>
01-02_Required_Elements_Reg_20150327_E+J	
02-00_20180424_Miniutes_Draft_Gases and Facilities_r2	
03-05_SEMI Staff Report 20180618_v1.0	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at [www.semi.org](http://www.semi.org). For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.